

Some EGS Studies...

- Compare with Geant4
 - Questions of range/cutoff parameters
- EM Resolution understood?
- Moliere radius – readout gap relation
- Input shower widths for fast MC
- Calibration requirement (electronics design)
- ECal depth – need to develop quantified criteria
 - EM energy containment
 - Is the HCal of any use for EM shower tails?
 - hadron interactions in the ECal – good or bad?
 - Transverse/long. segmentation for pattern recognition
 - photons and hadrons
 - Optimize coarser sampling with depth
- Minimum number of silicon layers (30? 25? 20??) = cost

EGS4 Setup

	1.5 mm	0.5	0.68	0.32	0.25	0.5	1.5
	W bulk	W thin	G10	Si	Air	W thin	W bulk
	E cut = 500 keV	100 keV	100 keV	100 keV		100 keV	500 keV
→	P cut = 500 keV	100 keV	100 keV	20 keV		100 keV	500 keV
	E stepe = 0.3%	0.3%	0.3%	0.3%		0.3%	0.3%

Config (=SiD sim): 30 x [5/7 X0 (2.5 mm) + 1.25 mm gaps]

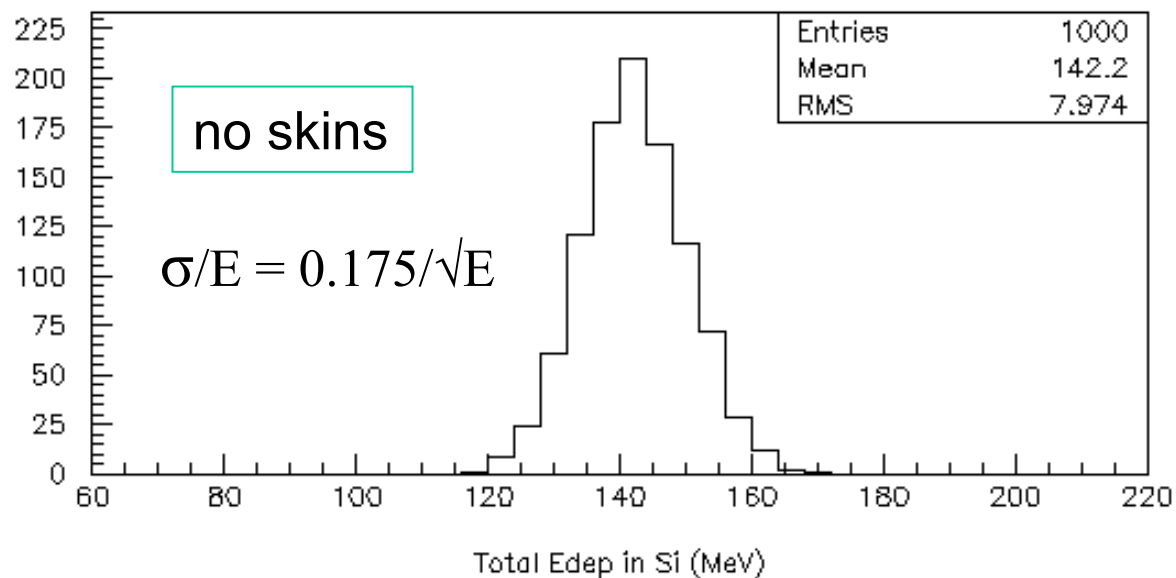
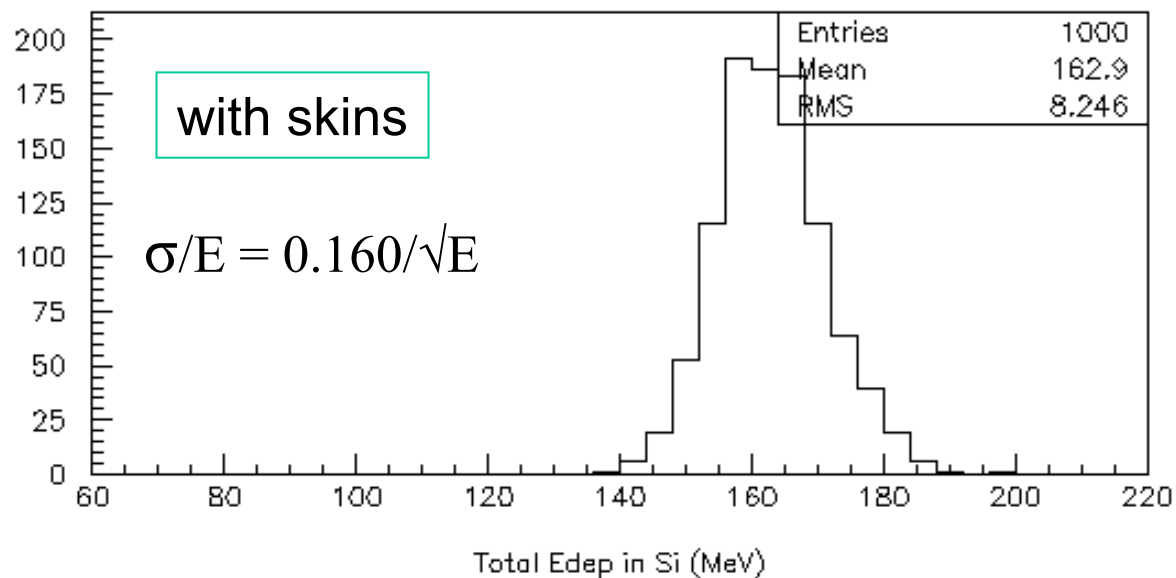
Thin EM sampling (Si)

If energy cutoffs (EGS) or range parameters (G4) are too large, then the simulated range of low energy secondaries exceeds the physical range

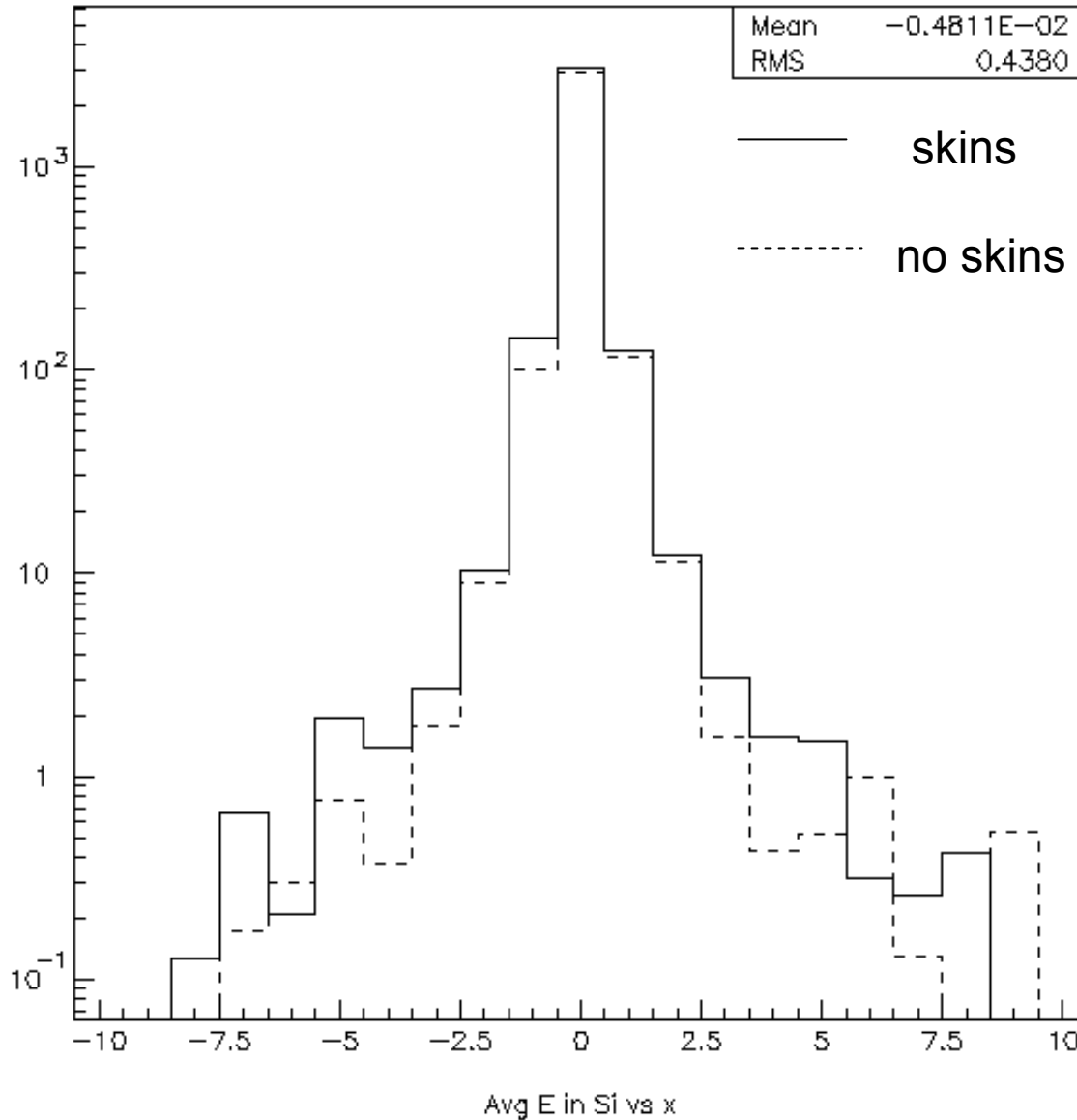
⇒ Their energy doesn't get deposited in the sensitive region.

Do we need the “skins” in this case?

- 10 GeV photons
- about 8x more CPU time to do it “right”



transverse spatial distributions (10 GeV photons)



E vs x at layer 4

Note: rms is 0.44 pixel
(2,2 mm)

Superb Position Resolution for 1 GeV Photons

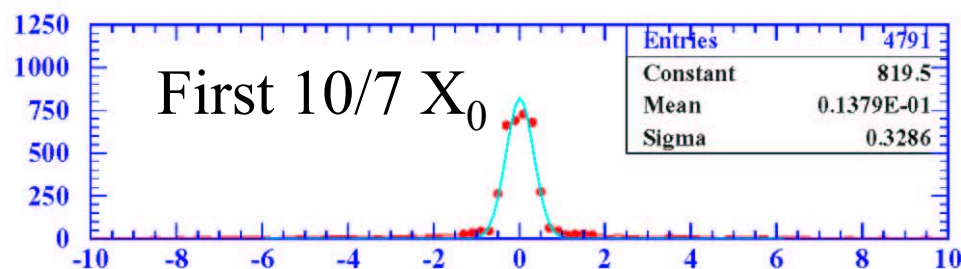
For illustration purposes only !:

Si-W, 42 layers,
1mm x 1mm pixels,

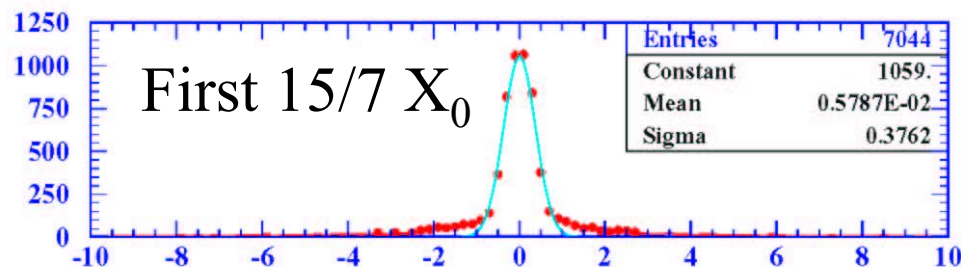
$R_M = 13.5$ mm

1 GeV photons

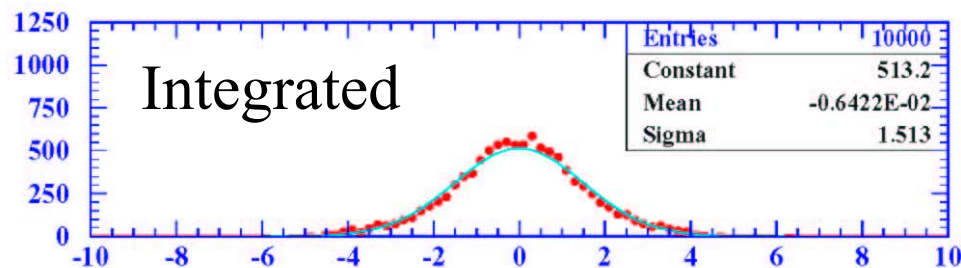
Transverse segmentations much finer than 5 mm may be useful – Si strips ?



330 μm



380 μm



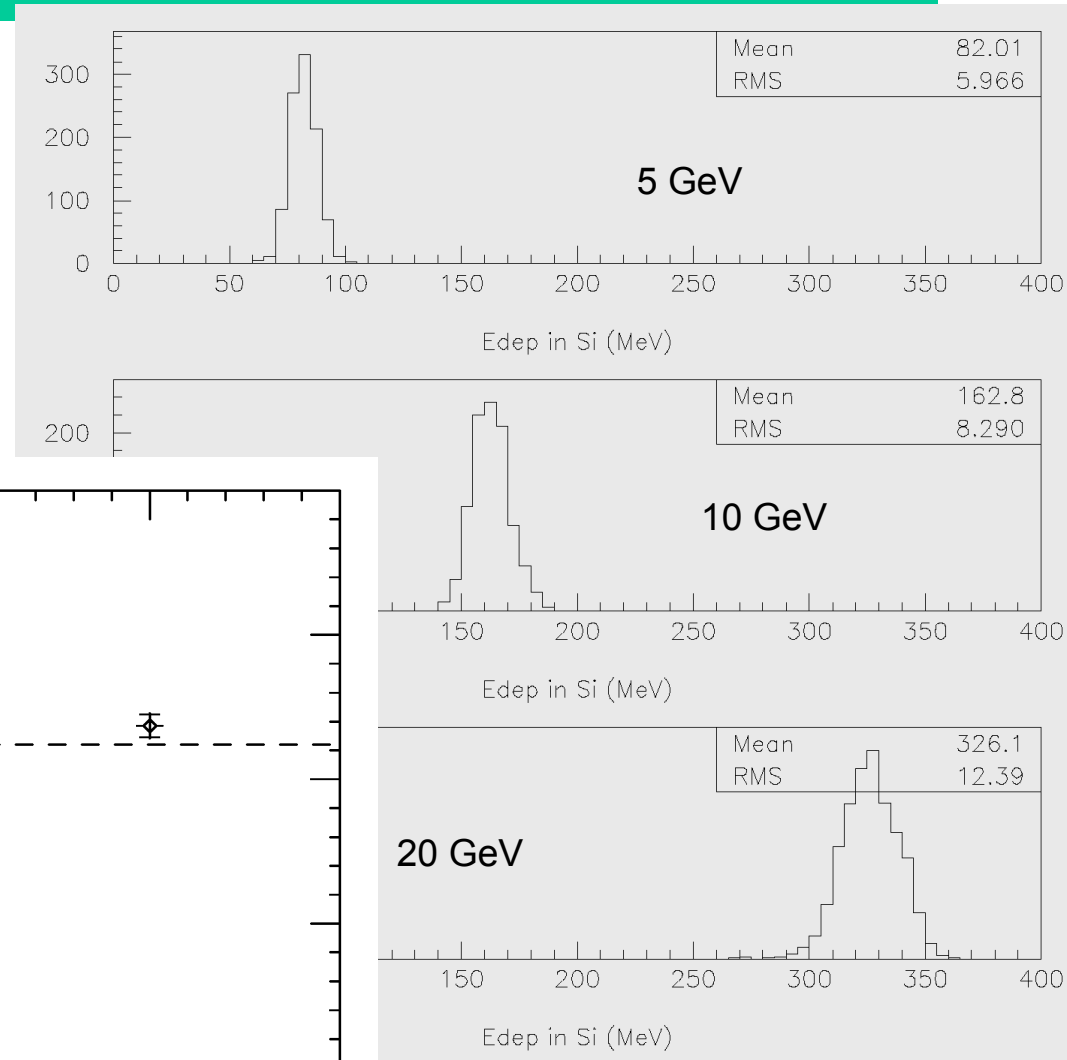
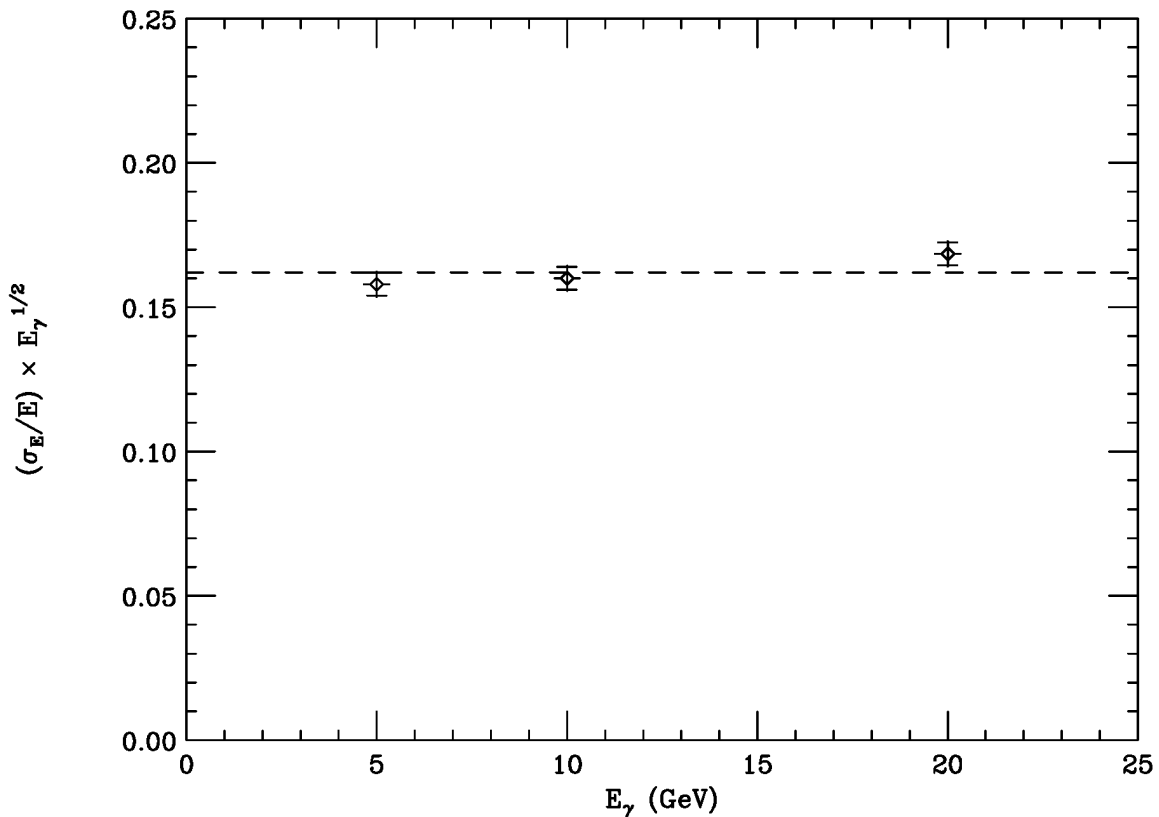
1500 μm

Position residual (mm)

energy resolution (photons)

use rms for width:

$$0.16/\sqrt{E}$$



Compare with Geant4

N. Graf, G. Wilson, RF

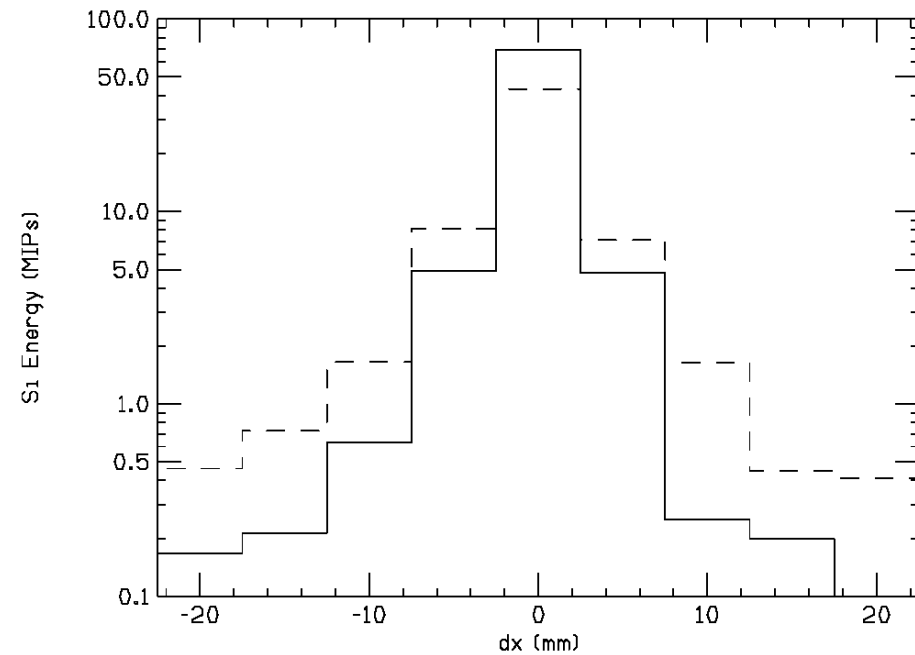
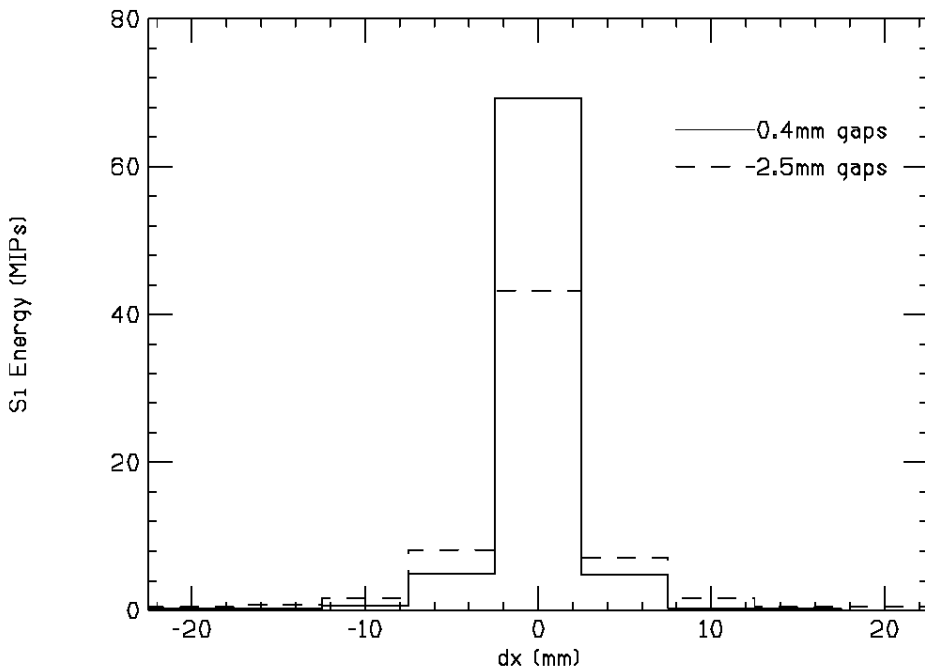
- Used infinite planes of 2.5 mm W + 1mm G10 + 0.4mm Si
- Found that Geant4 with (standard?) 1mm range cut underestimated the energy deposited in the silicon by 15-20% (and hence the standard Geant4 gets poorer energy resolution)
- Found convergence to EGS for a Geant4 range cut of 0.1mm (!)
- CPU time increases by factor 30

- Can make EGS approximate Geant4 with 1mm range cut by removing the skins and changing energy step from 0.3% to 2%

Effective Moliere radius - old

→ want to fill out the parameter space

- Standard SD: 5x5 mm² pixels with (1) 0.4mm or (2) 2.5mm readout gaps.
- 10 GeV photons; look at layer 10



Calibration

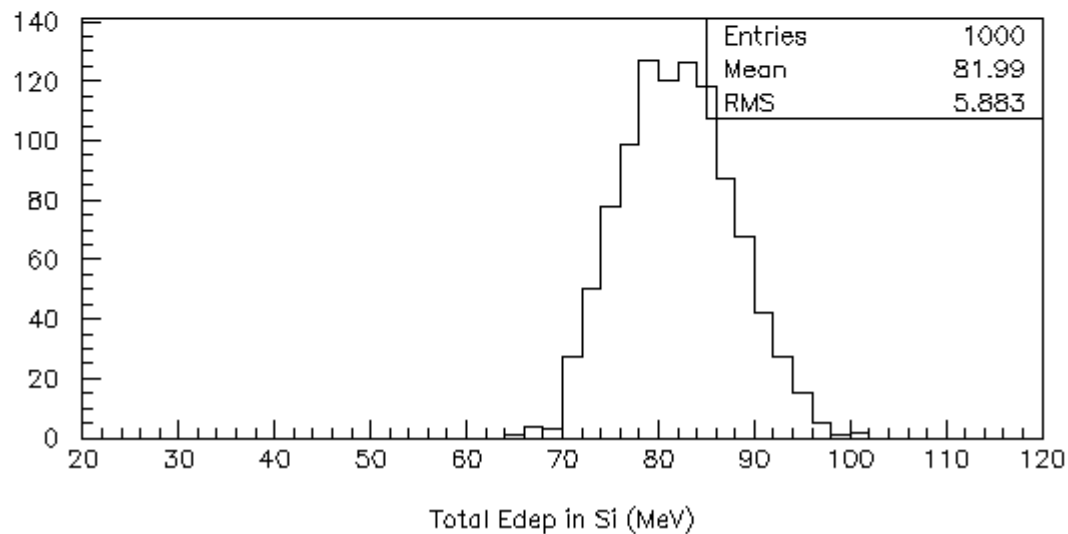
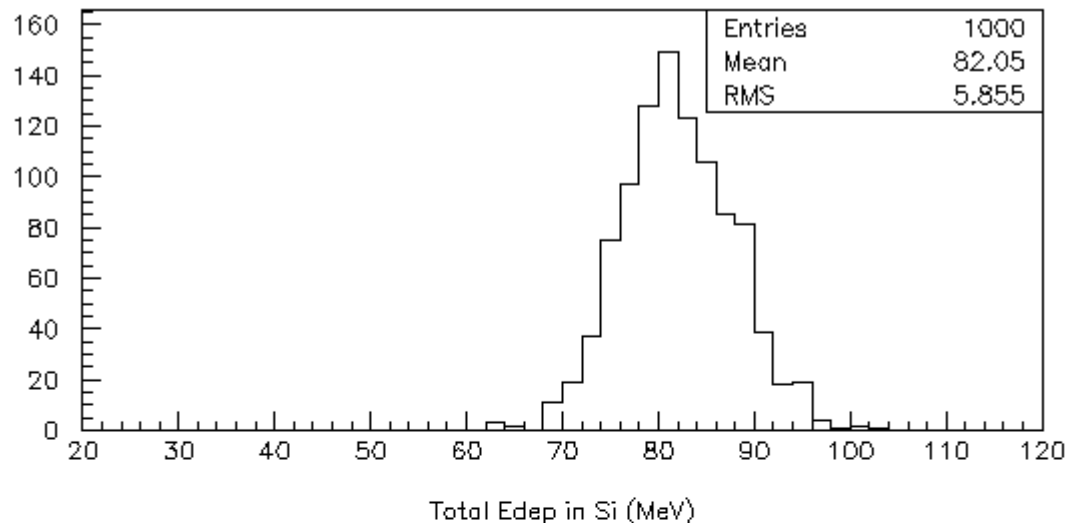
simulate effect of calibration errors:

- pixel to pixel (expect this to be small, < 1%)
- wafer to wafer (hope for 1 %)

Just starting....

5 GeV photons

- no pixel cal. error
- 2% error



Alternative Sampling Configurations – old study

50 GeV electrons

$30 \times 5/7 X_0$

$20 \times 5/7 X_0 + 10 \times 10/7 X_0$

- better containment
- poorer sampling

Cannot presently simulate the mixed config in standard SiD...

Graham: make it $40 \times 5/7 X_0$ but read out 10 of the last 20

